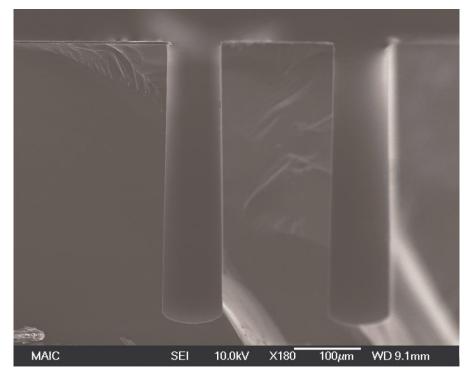
80 X 400μm Deep Etch Qual Recipe BAO2CAL

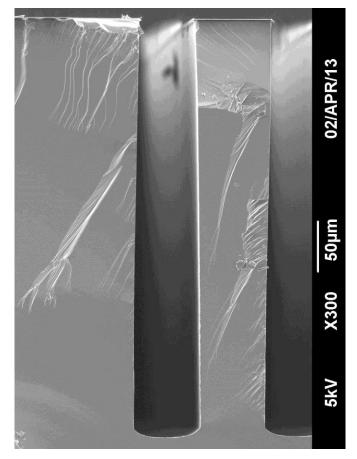
Original Qual



	Original	Now
Etch Rate (µm/min)	2.93	2.57
Non-uniformity	1.40%	1.36%
Selectivity	~90:1	~90:1
Profile	~90.59°	~90.63°

Today 60 X 400µm Deep

Did not have $80 \mu m$ feature on mask

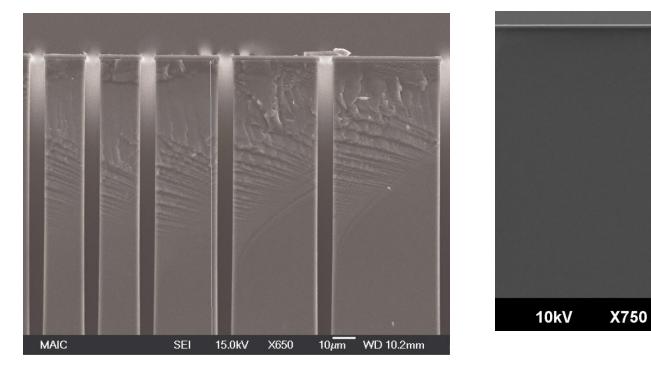


5 X 100µm Deep Etch Qual Recipe ProA

Original Qual

Today

20µm

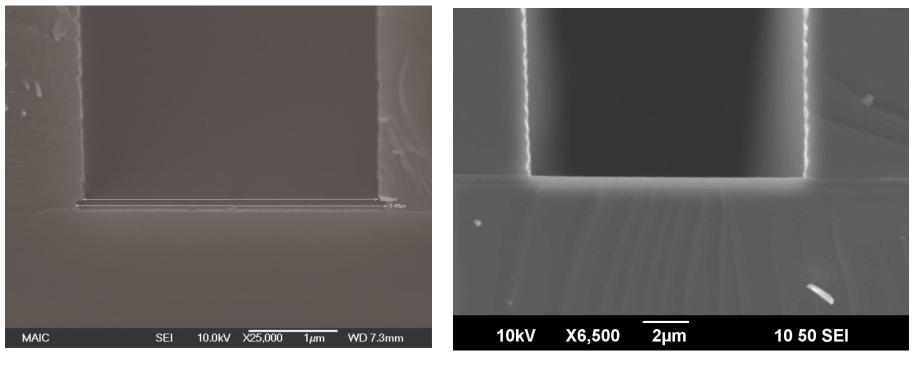


	Original	Now
Etch Rate (µm/min)	1.77	2.11
Non-uniformity	1.30%	0.85%
Selectivity	~60:1	~75:1
Profile	~89.9°	~89.9°

SOI Footing Functionality Recipe SOI_ETCH

Original Qual

Today (30% Over-etch)



	Original	Now
Etch Rate (µm/min)	1.86	2.21
Non-uniformity	-	-
Selectivity	~46:1	~150:1
Profile	~89.84°	~89.7°

New recipe to address grass formation issues in deeper etches on original recipe

Performed on pieces